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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In Re Application of:

Tsai et al.

Serial No.: 10/694,426

Filed: October 27, 2003

For: **Method of a Floating Pattern Loading System
in Mask Dry-Etching Critical Dimension
Control**

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) Group Art Unit: 1756

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) Examiner: Rosasco, Stephen D.

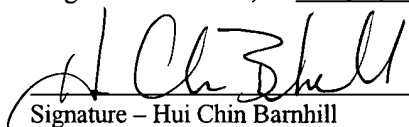
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) Confirmation No.: 3358

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) TKHR Docket: 252016-2470

) Top-Team: 0503-A30742US
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Certificate of Mailing

I hereby certify that this correspondence is being deposited with the United States Postal Service as first class mail, postage prepaid, in an envelope addressed to: Mail Stop Amendment; Commissioner for Patents, P.O. Box 1450, Alexandria, Virginia 22313-1450, on June 17, 2005.


Signature – Hui Chin Barnhill

RESPONSE TO RESTRICTION REQUIREMENTS

Mail Stop Amendment
Commissioner for Patents
P.O. Box 1450
Alexandria, Virginia 22313-1450

Sir:

The Office Action mailed May 19, 2005 has been carefully considered. In response thereto, please enter the following amendments and consider the following remarks.